

**PTSTANDARD**



# Mono Silicon Wafer

Data Sheet

**N-Type** 166±0.25mm

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# Mono Silicon Wafer

## Data Sheet

**N-Type** 166±0.25mm

### Material Performance Parameters

Conductivity Type	N	P/N type tester
Doped element	Phosphorus	/
Crystallinity	Single crystal	Priority etching technology (FSTM F47-88)
Dislocation density/pcs/cm <sup>2</sup>	≤500	Priority etching technology (FSTM F47-88)
Surface orientation	<100>±3°	X-ray diffractometer
Lateral crystal orientation	<010>, <001>±3°	X-ray diffractometer
Oxygen content (ppma)	≤11	FTIR (ASTM F121-83)
Carbon content (ppma)	≤1	FTIR (ASTM F123-91)
Lifetime (μs)	≥1000	BCT-400
Resistivity (Ω.cm)	0.6-1.6	Silicon wafer automatic inspection equipment

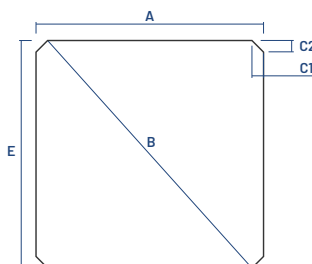
### Geometric Rule Parameters

Chamfered edge shape	Round	/
Wafer margins (mm)	166±0.25mm	Silicon wafer automatic inspection equipment
Wafer diameter (mm)	φ223±0.25mm	Silicon wafer automatic inspection equipment
Arc length projection (mm)	8.55±0.5mm	Silicon wafer automatic inspection equipment
Perpendicularity	90±0.15°	Silicon wafer automatic inspection equipment
Thickness specification (μm)	130±10	Silicon wafer automatic inspection equipment
	135±10	Silicon wafer automatic inspection equipment

### Appearance Quality

Surface quality	No visible pollution No color difference, No bright lines	Silicon wafer automatic inspection equipment
Edge Chipping	Depth≤0.3mm , Length ≤0.5mm Count ≤ 2/pcs, no V-shaped	Silicon wafer automatic inspection equipment
Saw mark (μm)	≤15	Silicon wafer automatic inspection equipment
Warp/bending degree (μm)	≤40	Silicon wafer automatic inspection equipment
TTV (μm)	≤25	Silicon wafer automatic inspection equipment
Micro-crack/void	None	Silicon wafer automatic inspection equipment

Wafer dimensions



Size: 166±0.25mm

A: 166±0.25mm

E: 166±0.25mm

B: φ 223±0.25mm

C1: 8.55±0.5mm

C2: 8.55±0.5mm